Supplementary Information

High–efficiency photoreduction of CO₂ in low vacuum

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References

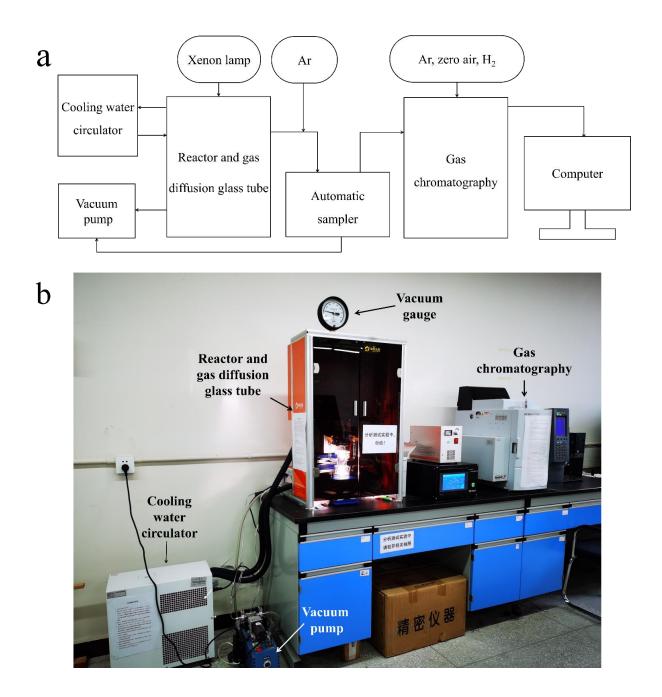


Figure S1. Photocatalytic CO₂ reduction system with online gas analysis. (a) Schematic and (b) photograph.

The total gas pressure:

$$P_{total} = P_{CO_2} + P_{H_2O}$$

According to the Ideal Gas Law:

$$P = \frac{nRT}{V}$$

Where P is the absolute pressure, V is the volume, T is the absolute temperature (T). n is the number of moles, R is the universal gas constant, 8.3145 J/mol K. In this system, R, T and V is constant. If we set,

$$a = \frac{RT}{V}$$

 $P = a \times n$

Then,

Thus,

$$P_{total} = P_{CO_2} + P_{H_2O} = a \times n_{CO_2} + a \times n_{H_2O}$$
$$n_{CO_2} = \frac{1}{a} \times P_{total} - n_{H_2O}$$

From the linear correlation between the absolute gas pressure and CO_2 content in Figure S2, the H₂O content in the system is constant and approximately 0.16 mmol.

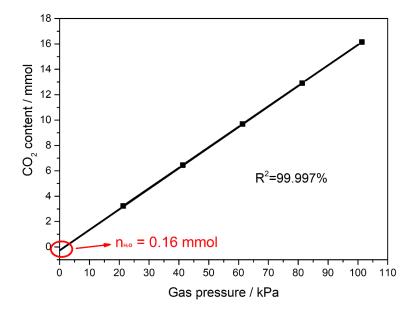


Figure S2. Absolute gas pressure vs. CO₂ content and the approximate H₂O content.

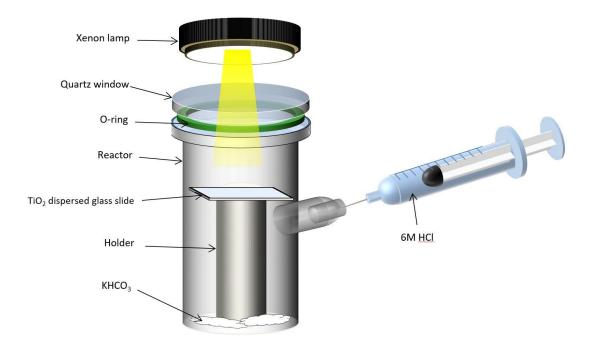


Figure S3. Schematic of the reactor.

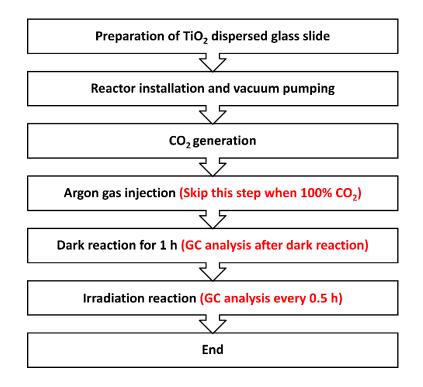


Figure S4. Experimental procedure in this work.

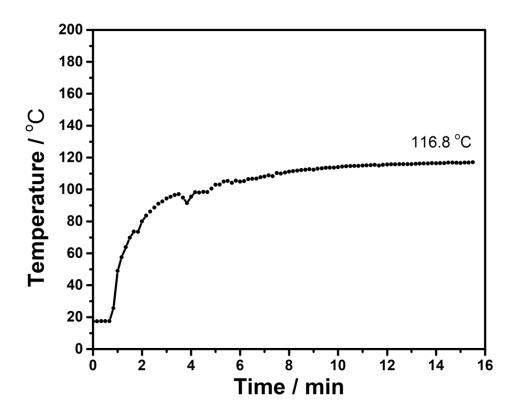


Figure S5. Temperature of the titanium oxide covered glass slide during irradiation.

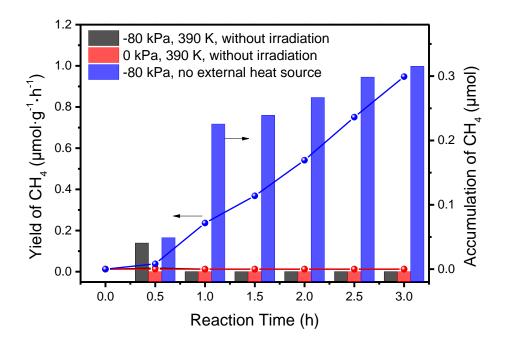


Figure S6. CH₄ yield at 390 K with and without irradiation.

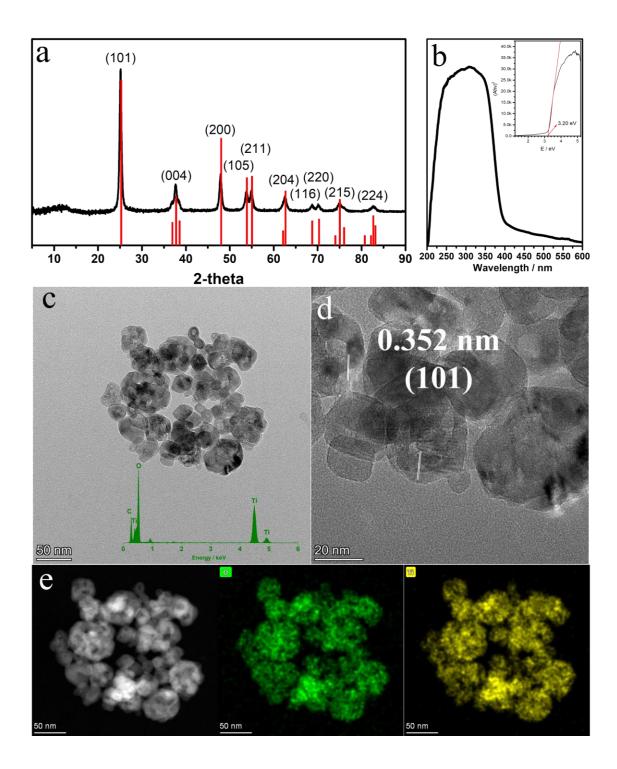


Figure S7. Physical characterizations of the commercial α -TiO₂. (a) XRD pattern of the commercial α -TiO₂. (101) is the most stable lattice plane. (b) Absorption spectrum of the commercial α -TiO₂ covered glass slide. Inset is the Mott-Schottky curve. (c-d) TEM images. Inset is the EDS spectrum. (e) HAADF image and the corresponding elemental mappings of O and Ti.

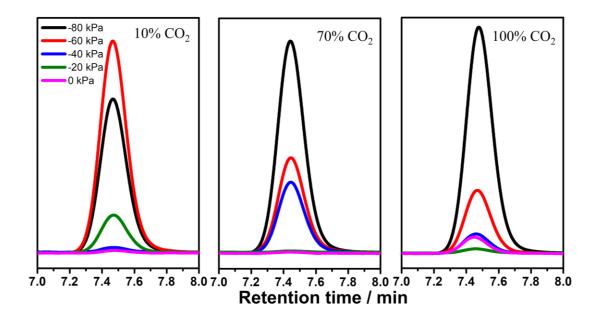


Figure S8. Gas chromatography curves of CH₄ in different CO₂ ratios.

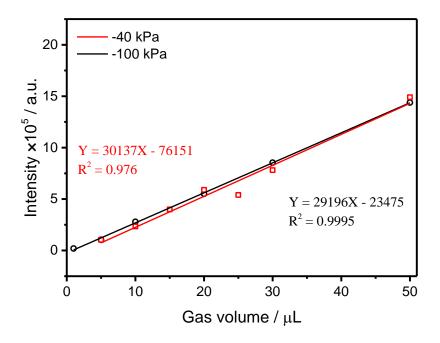


Figure S9. Calibration curves of the gas chromatography of CH₄ at different pressures.

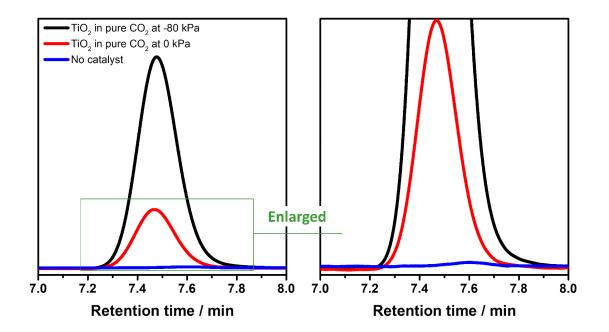


Figure S10. Gas chromatography curves of CH₄ with and without catalysts.

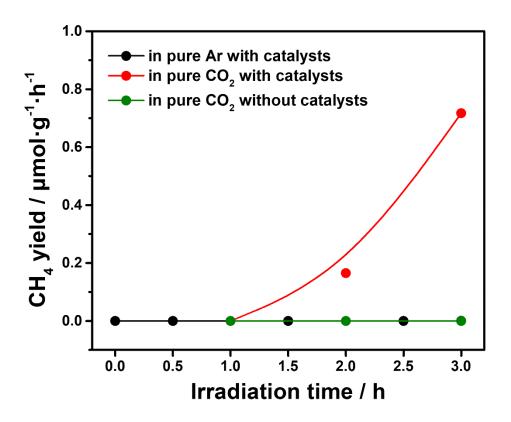


Figure S11. CH₄ yield in different vacuum degrees.

Unit (%)	10% CO2	70% CO ₂	100% CO ₂
-80 kPa	68.52	85	85.89
-60 kPa	64.89	73.5	89.368
-40 kPa	23.894	60.14	95.734
-20 kPa	37.93	95.19	53.987
-0 kPa	46.85		95.903

Table S1. CH₄ selectivity at various vacuum degrees.

The selectivity of CH₄ in the following discussion is calculated according to the following equation.

Selectivity_{CH₄} =
$$\frac{n_{CH_4}}{n_{CH_4} + n_{CO}}$$

where n is the mole number.

Table S2. CO production rate at different gas pressure and CO₂ content.

Unit (nmol g ⁻¹ h ⁻¹)	10% CO ₂	70% CO ₂	100% CO ₂	
-80 kPa	180.5	90.63	103.35	
-60 kPa	244.97	139.33	33.74	
-40 kPa	0 kPa 51.12		15.03	
-20 kPa	335.83	6.23	29.84	
0	5.23	6.01	9.34	

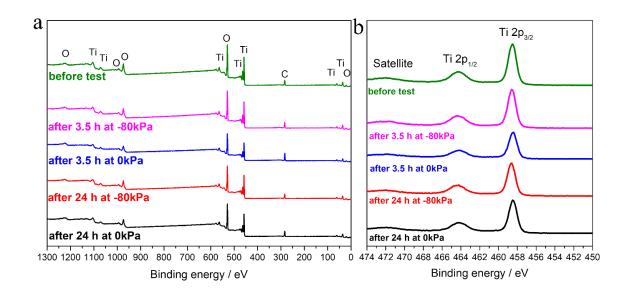


Figure S12. Binding energy evolution of the TiO₂ photocatalyst upon long-term stability test. (a) XPS survey spectra and (b) high-resolution XPS spectra of Ti 2p.

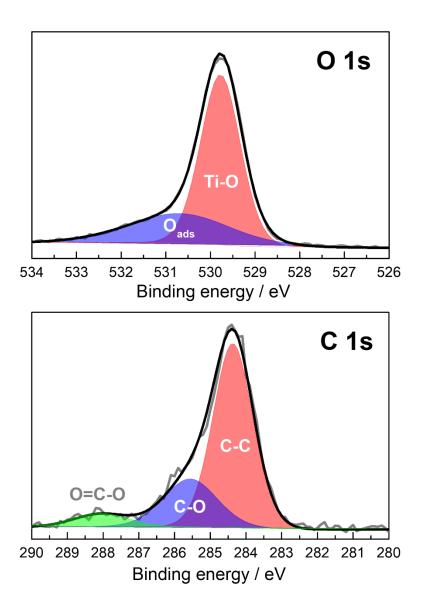


Figure S13. High resolution XPS spectra of O 1s and C 1s on commercial TiO₂ before stability test.

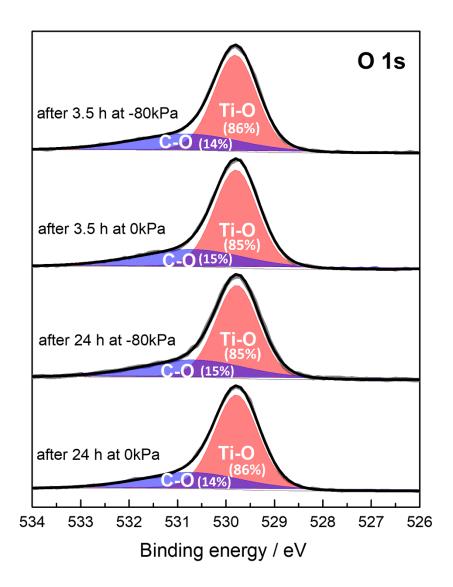


Figure S14. High-resolution XPS spectra of O 1s after running 3.5h and 24 h.

	Name	Peak BE	FWHM eV	Area (P) CPS.eV	Atomic %
	C-C	284.4	1.33	10197.72	74.94
Before test	C-O	285	1.32	2732.26	20.08
	O=C-O	288.1	1.81	678.06	4.98
	C-C	284.4	1.18	18375.97	80.83
3.5h at -80kPa	C-O	285	1.53	3968.54	17.46
	O=C-O	288.1	3.37	389.35	1.71
	C-C	284.4	1.14	15922.5	85.19
3.5 h at 0kPa	C-O	285	1.84	1372.62	7.34
	O=C-O	288.1	1.17	339.88	1.82
	C-C	284.4	1.32	8876.62	79.25
24 h at -80kPa	C-O	285	1.45	1730.15	15.45
	O=C-O	288.1	1.31	507.98	4.54
	C-C	284.4	1.2	10383.1	78.41
24 h at 0kPa	C-O	285	1.35	1970.19	14.88
	O=C-O	288.1	3.37	946.72	7.15

Table S3. Peak fitting parameters of C 1s.

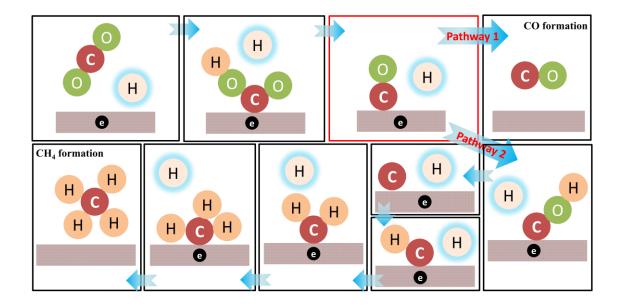


Figure S15. Mechanism of CO_2 photoreduction and the fundamental steps of CO_2 photoreduction in two pathways.

Generally, there are two pathways of CO_2 photoreduction. One is the formation of CO (following the equations S3–S5), the other is the formation of CH₄ (following the equations S3–S4, S6–S12). ^{1, 2}

$CO_2 + 2H \cdot \rightarrow HCOOH *$	(S3)
$HCOOH^* + H^{\bullet} \rightarrow CO^* + H_2O$	(S4)
Pathway 1: CO formation	
$CO^* \rightarrow CO$	(S5)
Pathway 2: CH ₄ formation	
$CO^{*+}H^{\bullet} \rightarrow COH^{*}$	(S6)
$COH^* + H^{\bullet} \rightarrow C^* + H_2O$	(S7)
$C^* + H^{\bullet} \rightarrow CH^*$	(S8)
$CH^* + H^{\bullet} \rightarrow CH_2^*$	(S9)
$\mathrm{CH}_2^* + \mathrm{H} \cdot \to \mathrm{CH}_3^*$	(S10)
$CH_3^* + H^* \rightarrow CH_4^*$	(S11)
$CH_4^* \rightarrow CH_4$	(S12)

When CO* on the surface of TiO_2 continued to obtain electrons and protons forming COH*, CH₄ generated; otherwise, CO generated.he faster those electrons and H⁺ were transferred, the higher CH₄ yield.

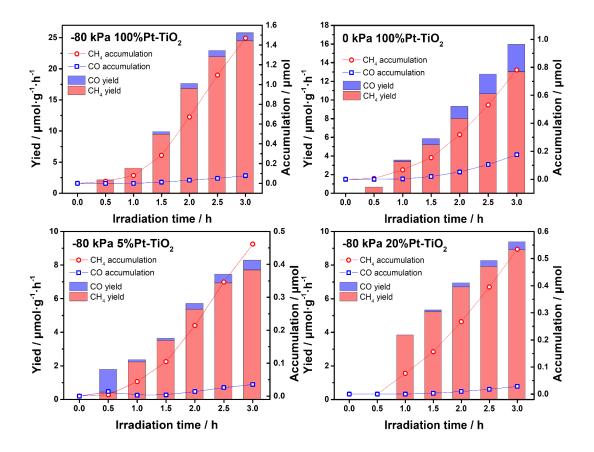


Figure S16. CH₄/CO accumulation and yield of the Pt-TiO₂ catalyst at -80 kPa and 0

kPa.

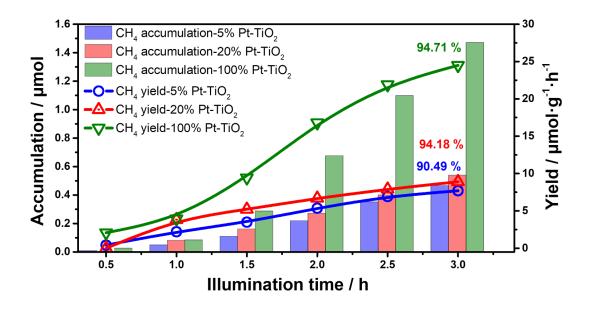


Figure S17. CH₄ accumulation and yield from photocatalytic CO₂ reduction on Pt–TiO₂ catalysts at -80 kPa in pure CO₂. CH₄ selectivity were 94.71%, 94.18%, 90.49% with 100%, 20% and 5% Pt-TiO₂, respectively. For all catalysts, the loading was 20 mg.

References

- Z. Geng, Y. Cao, W. Chen, X. Kong, Y. Liu, T. Yao and Y. Lin, *Appl. Catal.*, *B*, 2019, 240, 234-240.
- 2. J. Fu, K. Jiang, X. Qiu, J. Yu and M. Liu, Mater. Today, 2020, 32, 222-243.